

Notice of References Cited	Application/Control No. 10/658,687		Applicant(s)/Patent Under Reexamination YOSHIMURA, HIROYUKI	
	Examiner Maureen G. Arancibia		Art Unit 1763	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,580,639	12-1996	Togawa et al.	428/156
	B	US-6,613,459	09-2003	Saito et al.	428/692
	C	US-5,998,261	12-1999	Hofmann et al.	438/257
	D	US-5,770,465	06-1998	MacDonald et al.	216/2
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Etch Rates for Micromachining Processing" by Williams et al. Journal of Microelectromechanical Systems, Vol. 5, No. 4, December, 1996, pages 256-269.
	V	"Ferrite devices" by Chin. In AccessScience@McGraw-Hill, http://www.accessscience.com , DOI 10.1036/1097-8542.254100, last modified: January 28, 2002. Downloaded on 09/27/2004.
	W	JPO Machine English Translation of Japanese Publication 11-339242. Obtained from http://www19.ipdl.jpo.go.jp/ on 09/28/2004.
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.